

## Supplementary Information

### Facile Ion-exchange Synthesis of Silver Films as Flexible Current Collectors for Micro-Supercapacitors

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#### Calculation

To achieve the Ragone plot, the power density ( $P$ ) and energy density ( $E$ ) can be calculated from the data of cyclic voltammetry measured at the scan rates of 0.01~500 V s<sup>-1</sup>

The capacitance values of SMIE-MSCs were calculated from the CV data according to the following equation (1):

$$C_{cell} = I/(dV/dt) \quad (1)$$

Where  $I$  refers to the mean current in the CV curves;  $dV/dt$  refers to the scan rate in CV curves

The area and stack capacitance values of SMIE-MSCs were calculated according to the following equation (2) and equation (3):

$$C_A = 2 \times C_{cell}/A \quad (2)$$

$$C_V = 2 \times C_{cell}/V \quad (3)$$

Where  $C_{cell}$  is the capacitance of the 2-electrode cell,  $A$  and  $V$  refer to the surface area and volume of the device at one electrode, respectively.

The energy density and power density were calculated according equation (4) and equation (5):

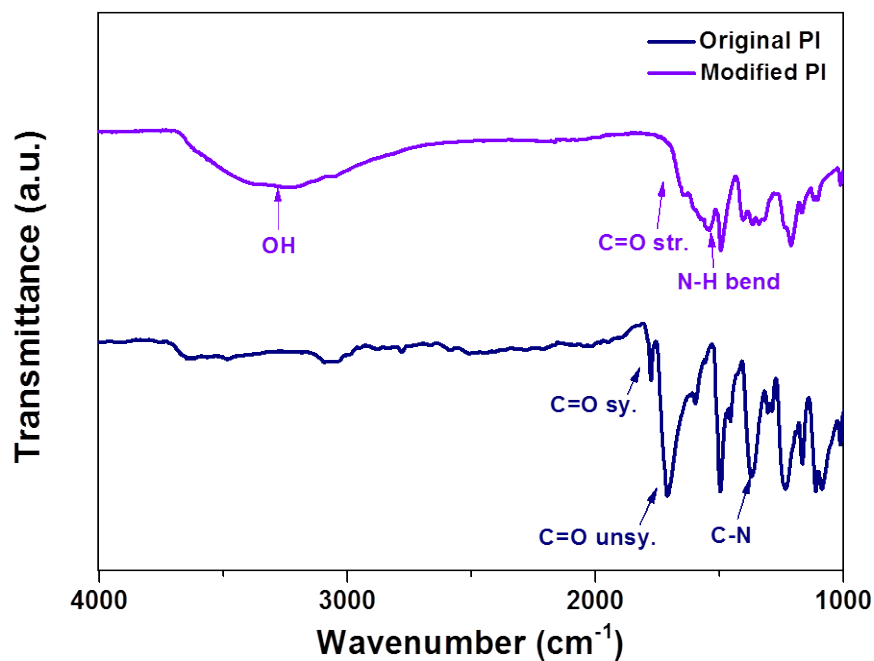
$$E = \frac{1}{2} \times \frac{C_V \times (\Delta V)^2}{3600} \quad (4)$$

Where  $E$  is the energy density (Wh/cm<sup>3</sup>),  $C_V$  is the stack capacitance and  $\Delta V$  is the discharge

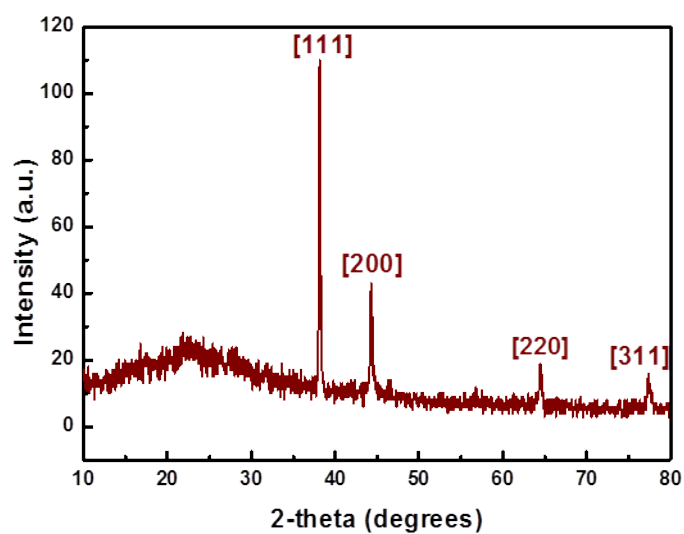
voltage range (V).

$$E = \frac{1}{2} \times \frac{C_V \times (\Delta V)^2}{3600} \quad (5)$$

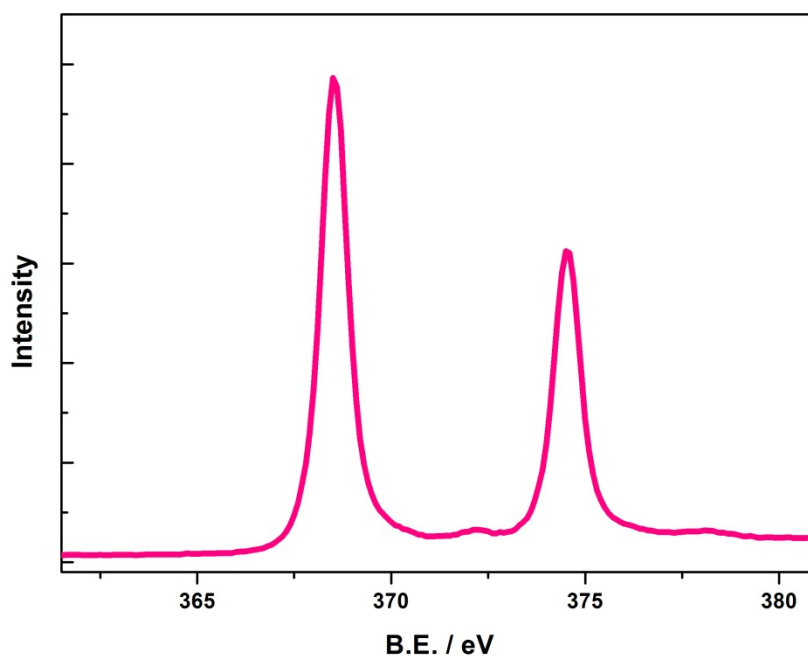
where  $P$  is the power density ( $\text{W}/\text{cm}^3$ ),  $E$  is the volumetric energy density and  $t$  is the discharge time (s)



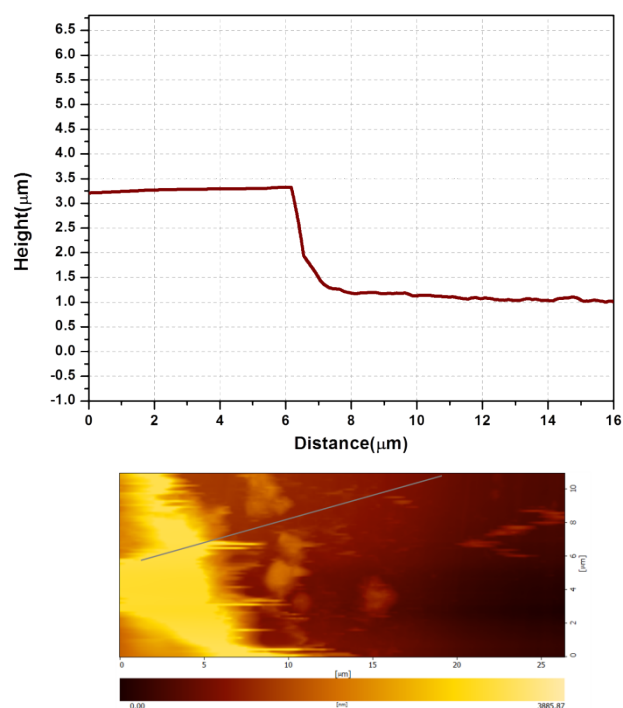
**Fig. S1** FTIR image of original PI and modified PI. The peaks at 1775 and 1718  $\text{cm}^{-1}$  are related to C=O symmetric vibration and unsymmetric vibration, respectively, and the peak at 1370  $\text{cm}^{-1}$  is related to C-N vibration. After KOH modification, above peaks are weakened and diminished strongly. Two new peaks corresponding to C=O stretching and N-H bending appear, which is attributed to the hydrolytic cleavage of the imide groups contained in the repeating unit of PI.



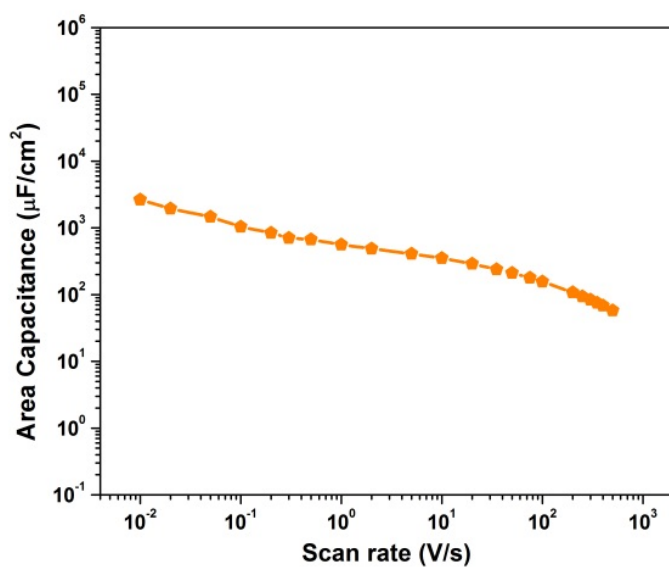
**Fig. S2** XRD image of SMIE-Ag. From the figure, it can be seen that four diffraction peaks, corresponding to [1 1 1], [2 0 0], [2 2 0], [3 1 1], respectively, can be found between 30° and 80°, indicating that the films are constructed by face-centered cubic Ag crystalline particles.



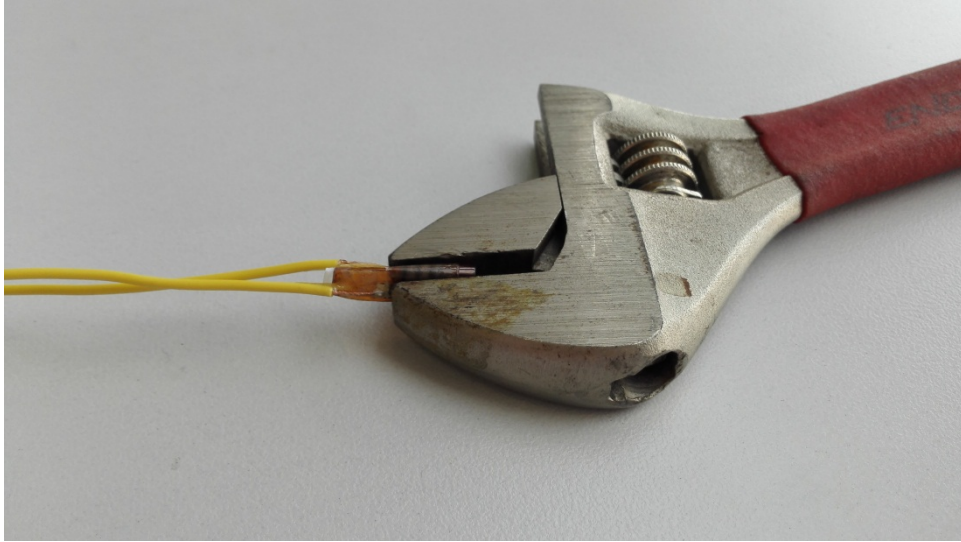
**Fig. S3** XPS image of SMIE-Ag. The Ag 3d peaks confirm the formation of Ag.



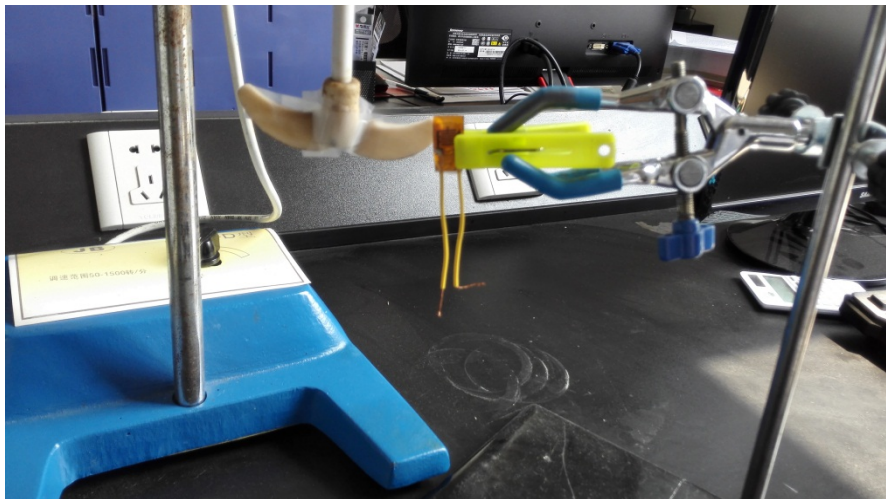
**Figure S4.** AFM image and height profile of Electrode on SMIE-MSCs. The thickness of the IDEs is about 2 μm. A clear gap exists between substrate and IDEs.



**Figure S5.** Specific area capacitance at different scan rates



**Figure S6.** Setup for static mechanical test. SMIE-MSCs are mounted onto a spanner. Controlling two clamps, CV tests can be done in different bending radii.



**Figure S7.** Setup for dynamic mechanical test. The blade of machine can cause the bending state on the free-end of MSCs.